Electron deposition in semi-infinite media / Electron backscatter Geant4 Validation

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Experimental setup and Geant4 simulation application

4 Simulation Results

- General aspects
- Part I: Energy deposition in semi-infinite media
- Part II: Backscatter

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- 2 Geant4 Physics
- 3 Experimental setup and Geant4 simulation application
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GEANT4 electron transport in matter

Large-scale validation study of Geant4 EM physics was performed:

* Low-energy domain (< 1 MeV) examined

* Significant physics observables systematically investigated (energy deposition, backscatter)

* First results available

* Important impact on future Geant4 developements

* Significant guidance for users

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Validation of Geant4 physics models

- Major goals
 - Guidance for users
 - Providing hints for optimal configuration of simulation parameters
 - Highlighting the abilities of physics models
 - Feedback for developers
 - Improvement of models based on findings

Systematic studies

- Investigation of systematic conditions (Many materials, beam energies,...)
- Can enormously facilitate the interpretation of the overall behaviour of models

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Validation of Geant4 physics models (cont.)

Strategy and methods

- Modeling physics scenarios
- Building simulation applications
- Computation of relevant physical quantities
- Comparison against experim. data
- Comparison against reference data



e.g. NIST

Experimental validation approach

- Not trivial, since experimental conditions must be reproduced
- Precise geometry setup required in simulation application
- Physical quantities computed according to experimental measurement

Physics observables in the current validation process

Low-energy electron beams (<1MeV) incident on diff. materials:

- Electron energy deposition in semi-infinite media
 - Spatial energy delivery as a function of depth
- Backscattered particles
 - Backscattered fractions of primary electrons and electron energy

Quantitative Geant4 Validation

- Validation of low-energy electromagnetic physics models
- Comparison against experimental data (Sandia reports SAND79-0410.UC-34a and SAND80-1968.UC-34a)

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Sandia validation data

- Measured for Monte Carlo validation purposes (TIGER code)
- Electron energy deposition values are absolute
 - Important issue in a physics validation process
 - Hardly found in literature
 - Measured with a high spatial resolution
 - Uncertainty claimed to be < 2.2%
 - Potential drawback: Systematic erros fully considered?
- Many different materials covered
 - From beryllium to uranium
- Varying beam energies and incident angles considered
 - 300keV 1MeV (Energy deposition measurements), 28keV 1MeV (Backscatter measurements)
 - 0° and 60° (Energy deposition measurements), 0°, 15°, 30°, 45°, 60°, 85° (Backscatter measurements)

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Low-energy EM physics in Geant4

Selectable physics models

- Process implementations based on different principles available
- Parametrized and analytical models offered
- Combining models adequately is the user's responsibility
 - Makes toolkit more versatile but requires certain experience by the user
 - Guidelines given in examples and in "Geant4 User's Guide for Application Developers"
 - Pre-prepared physics lists available

• EM processes for e^- and γ in the low-energy domain

- Two packages: Low-Energy and Standard
- Low-energy package: Two different approaches available
 - Library-based (Livermore) models
 - Penelope-like models

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Low-energy EM physics in Geant4 (cont.)

Overview of EM processes



Standard G4MultipleScattering used for simulations involving processes of the Low-energy package

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Simulation configuration

Parameters (optionally handled by the user)

- Maximum step size of particle
 - Determines accuracy of spatial resolution
 - Recommended: Size of the order of the scoring bins
- Production threshold for generating secondaries
 - Lower limits: Liverm. 250eV, Penelope \sim 100eV, Standard 1keV
 - Handled through a range cut parameter
 - δ-ray production can significantly alter energy deposition
- Multiple-scattering step limitation
 - More Multiple-scattering parameters exists (not further considered)

Tracking

- No tracking cut exists in Geant4
 - All (produced and accepted) particles tracked to zero range
 - Secondary production can be controlled though (prod. threshold)

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Calorimetric measurements

• Spatial energy delivery pattern

- Calorimeter foil placed between front layer and "infinite" layer
- Calorimeter consists of same material as target
- Energy deposition measured for different front layer thicknesses
- Measurement depth = Front layer thickness + half the calorimeter thickness

Backscattered energy

- Energy deposition determined in target (bulk calorimeter)
- Backscattered energy calculated as complement of measurement
- (Theoretical) Bremsstrahlung-correction applied



Geometry

Semi-infinite target medium

Lateral dimensions and thickness
> maximum e⁻-range

Primary particle vertex

- Direction determined by angle α between surface normal and beam axis
- Beam impinges at target surface center



Simulation code

Geant4 application

 Simulation application was developed according to the experimental setup

Target/Detector modeling

Elaborate software design for describing target/detector geometry:

- * Decorator design pattern applied (see figure)
 - Add-on layer can be placed dynamically in front of semi-infinite slab
 - Multi-slab geometry by nesting decorator (AddOnTargetLayer) recursively
- * Facilitates future work involving multi-layer configurations



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Simulation results

Systematic validation approach against Sandia data

- Various experimental configurations were investigated
 - Different target materials
 - Varying beam energies and incident angles
- Several simulation configurations evaluated
- Small subparts covered earlier by other authors (but no comprehensive collection)
 - E.g. O. Kadri *et al*,"Geant4 simulation of electron energy deposition in extended media", NIM B 258 (2007) 381-87

• Due to lack of time only a subset of results can be presented

- Focus is on certain aspects
- Paper with a complete collection of results in preparation with

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Simulation results (cont.)

• Setups and configurations considered in the presentation

- Systematic results presented for a few materials
- Few beam energies considered
- Geant4 versions 8.1-p02 and 9.0-p01 compared (for energy deposition results only)
 - Differences due to Multiple-Scattering model (Standard package)
 - Low-Energy package (Livermore, Penelope models) remains the same in both versions
- Secondary particle production threshold evaluated

Further settings

- Maximum step size always set to 0.001 mm (lower recommended value)
- Default value taken for Multiple-Scattering step limitation

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Beam axis \neq surface normal: Incident angle of 60°



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Generation of secondaries: Influence of production threshold

Liverm. library based processes

Energy deposition

- Significant dependence on cut in range for Fe, Cu, Mo, Ta (for all considered beam energies)
- Peak: Differences up to 15% observed
- Effects due to angular distribution of secondary particles

Low prod. threshold (250eV)

- Underestimation of peak height for 1MeV beams
- Was rather stopping power measured? (Then higher cut would apply)



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Summary (Part I)

Geant4 Livermore models

- Capable of reproducing experimentally measured spatial energy deposition for most materials with good precision
- Some deficiencies in peak region observed (Experimental conditions correctly reproduced?)
- Choice of production threshold for generating secondary particles significantly influences spatial energy deposition in high-Z materials

8.1-p02 vs 9.0-p01 (latest release)

- Considerable difference for low-Z materials
- Effects due to Multiple-Scattering model

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Low-Z material:

* Good agreement between simulation and experimental data for some angles

* Underestimation at low beam energies (109keV) and large angles

⇒ Playground for further investigation of Multiple-Scattering parameters

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70

80

E = 0.109MeV

Angle of Incidence (deg)

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Generation of secondaries: Influence of production threshold

Low production threshold (250eV)

- Can improve backscatter results (both, backscattered fraction of energy and charge)
- See plots (Molybdenum, 109keV beam)
- Systematics not discussed here (More information to be found in publication)



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Summary (Part II)

Geant4 Livermore models

- Very good reproducibility of backscattered fractions of energy except for some deficiencies at beryllium
- Multiple-Scattering parameters to be investigated in more detail for low-Z materials

Thank for your attention!